

# Full-Band and Atomistic Simulation of Realistic 40nm InAs HEMT

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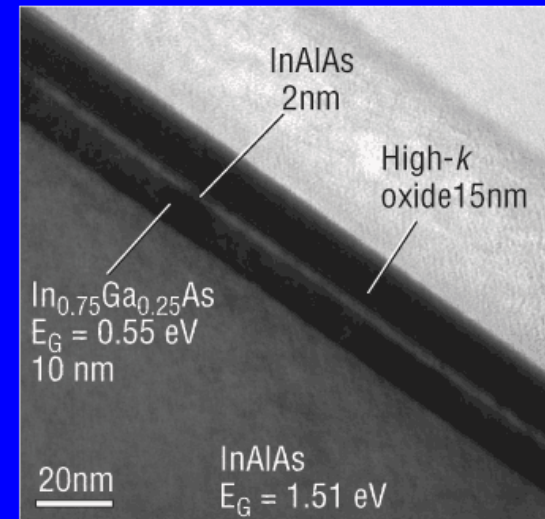
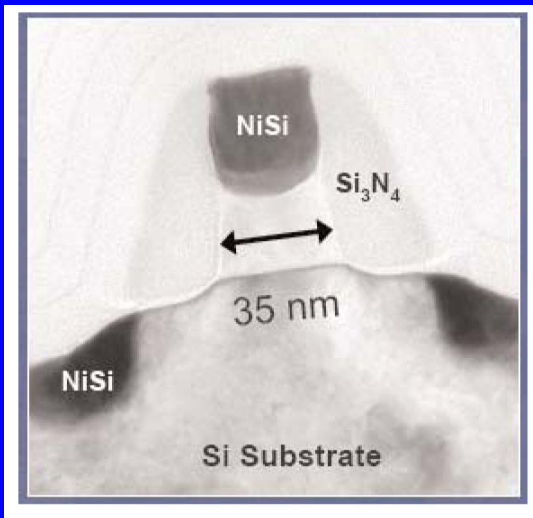
***Network for Computational Nanotechnology and  
Birck Nanotechnology Center, Purdue University***

# Motivation: Towards III-V MOSFET

**Expectation: High Speed (Mobility), Low Power Consumption**  
**On Chip Integration of Electronics and Optics**

**Challenges : Oxide Layer (high- $\kappa$ ), p-doped Transistors**

65nm Node Devices  
 $L_G = 35\text{nm}$



**INTEL**

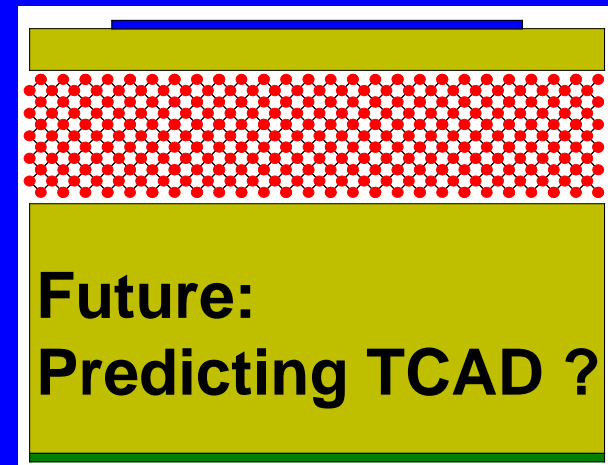
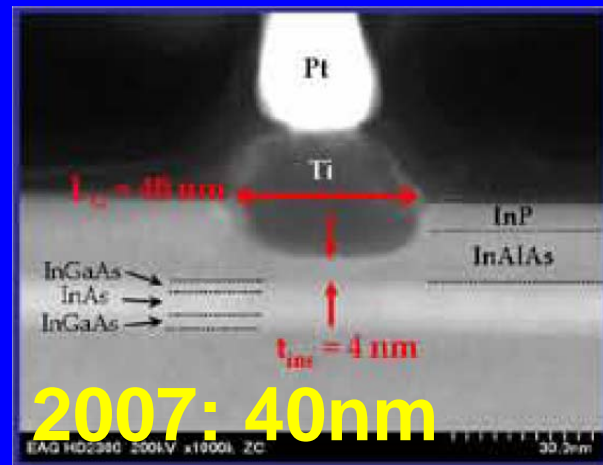
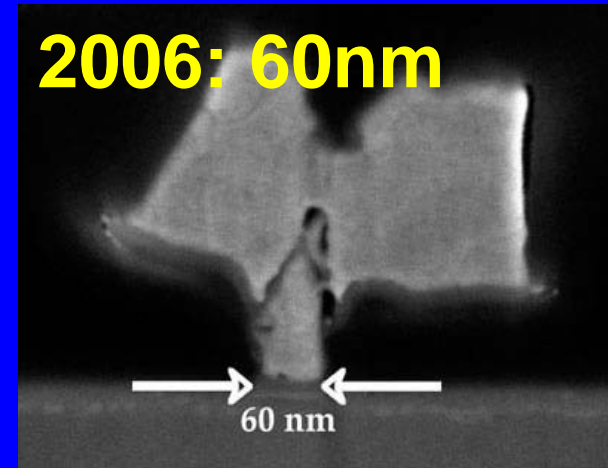
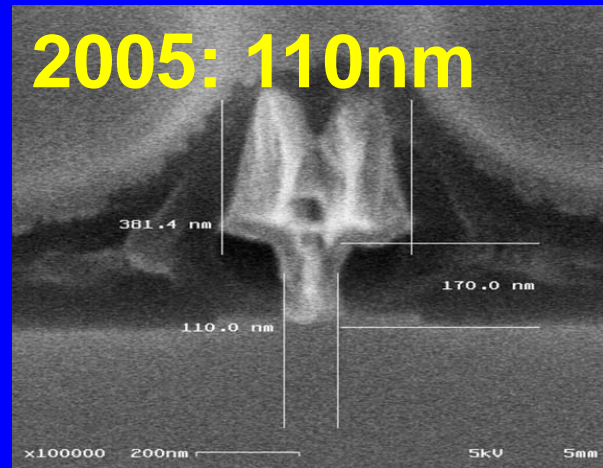
**FREESCALE**

[http://download.intel.com/technology/silicon/silicon\\_paper\\_06.pdf](http://download.intel.com/technology/silicon/silicon_paper_06.pdf) and

[http://www.solid-state.com/display\\_article/346921/5/none/none/Feat/III-V-MOSFETs-for-future-CMOS-transistor-applications](http://www.solid-state.com/display_article/346921/5/none/none/Feat/III-V-MOSFETs-for-future-CMOS-transistor-applications)

# Intermediate Step: III-V HEMTs

Lot of Recent Advancement by del Alamo's Group at MIT  
Every Year Devices with a Shorter Gate Length Introduced



# Outline

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- **Motivation**
- **Simulation Approach**
  - Bandstructure and Transport
  - Multi-Scale Domain Decomposition
- **Performance Analysis**
  - $I_d$ - $V_{gs}$ ,  $I_d$ - $V_{ds}$
  - Transconductance
- **Challenges and Open Issues**
  - Injection Velocity, Leakage Current
- **Conclusion and Outlook**

# Simulation Approach

# Bandstructure Model

## Nearest-Neighbor $sp^3d^5s^*$ Tight-Binding Method

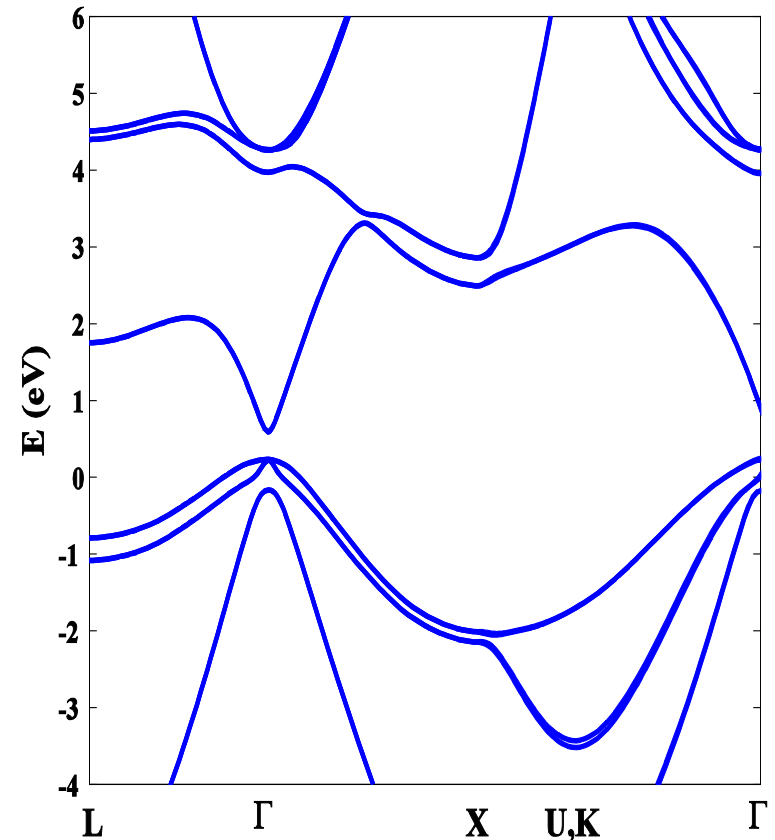
### GOOD:

- bulk CB and VB fitted
- extension to nanostructures
- atomistic description
- alloy disorder (InGaAs)
- strain relaxation

### BAD:

- high computational effort
- semi-empirical model

### InAs Bandstructure

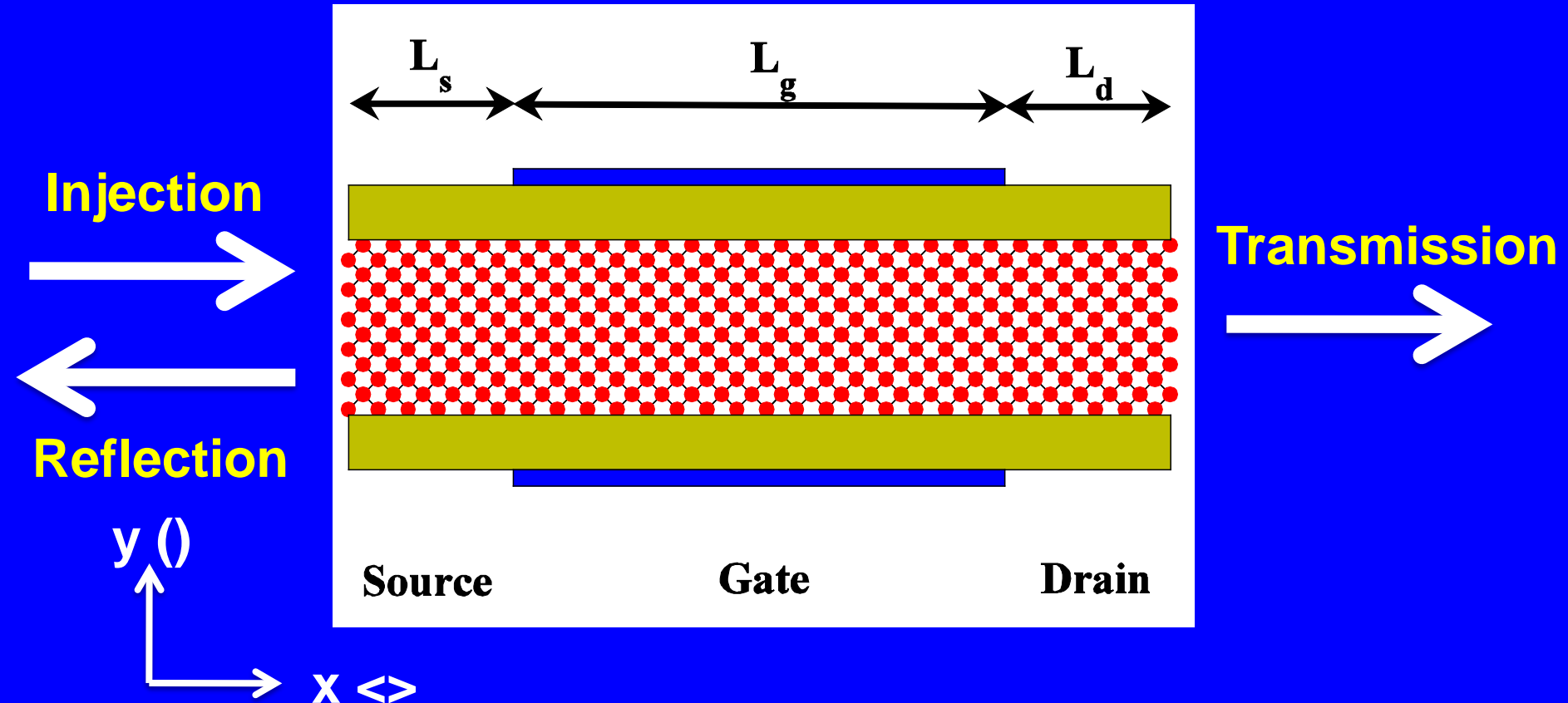


# Transport Model (1)

Atomistic and Full-Band Transport: NN  $\text{sp}^3\text{d}^5\text{s}^*$  T-B Model

x: transport direction / y: confinement / z: periodic

States Injected at different Energies  $E$  and Wavevector  $k_z$



# Transport Model (2)

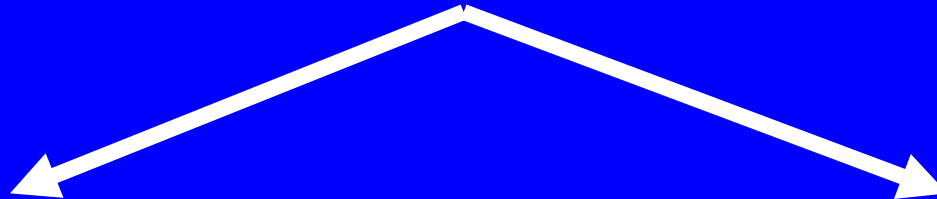
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## 2D Schrödinger Equation

$$H / \psi_E > = E / \psi_E >$$

Tight-Binding Ansatz for the Wave Function

$$< r | \psi_E > = \sum_{\sigma, ijk, k_z} C_{ij}^{\sigma}(E, k_z) \Phi_{\sigma}(r - R_{ijk}) e^{ik_z z_k}$$



$$(E-H-\Sigma) \cdot G^R = I$$

Matrix Inversion

$$(E-H-\Sigma) \cdot C = I n_j$$

Linear System of Eq.



# Transport Model (2)

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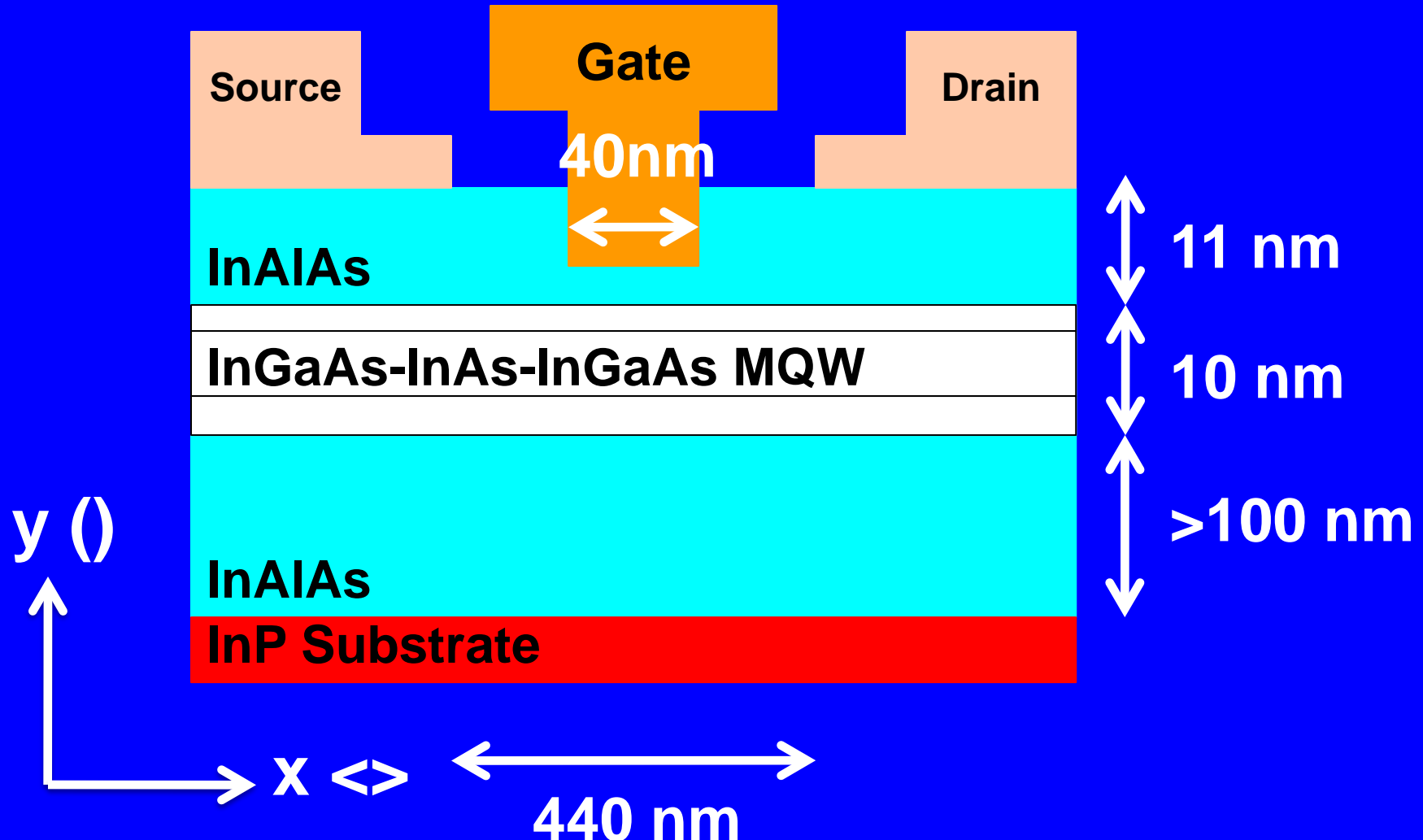
- Linear System of Eq.  $Ax=b$
- Size of A: number of atoms times number of orbitals per atom
- ~1000 Energies, 15-30 Momentum
- Parallel Approach
- 2D Domain limited to 15x200 nm<sup>2</sup>
- Multi Scale Decomposition

Matrix Inversion

Linear System of Eq.

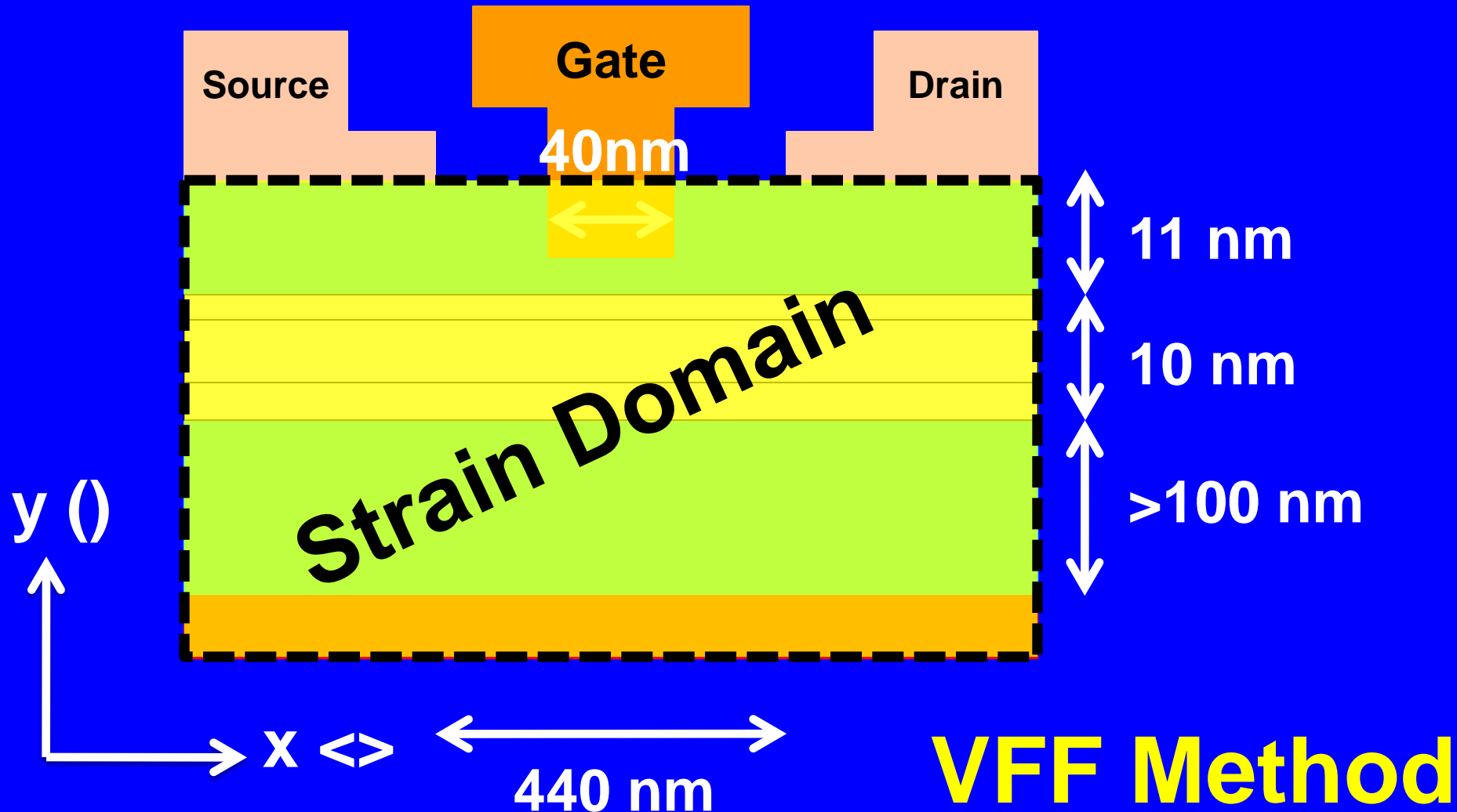
# Multi-Scale Domain Decomposition (1)

Device Structure: Transport, Poisson, Strain



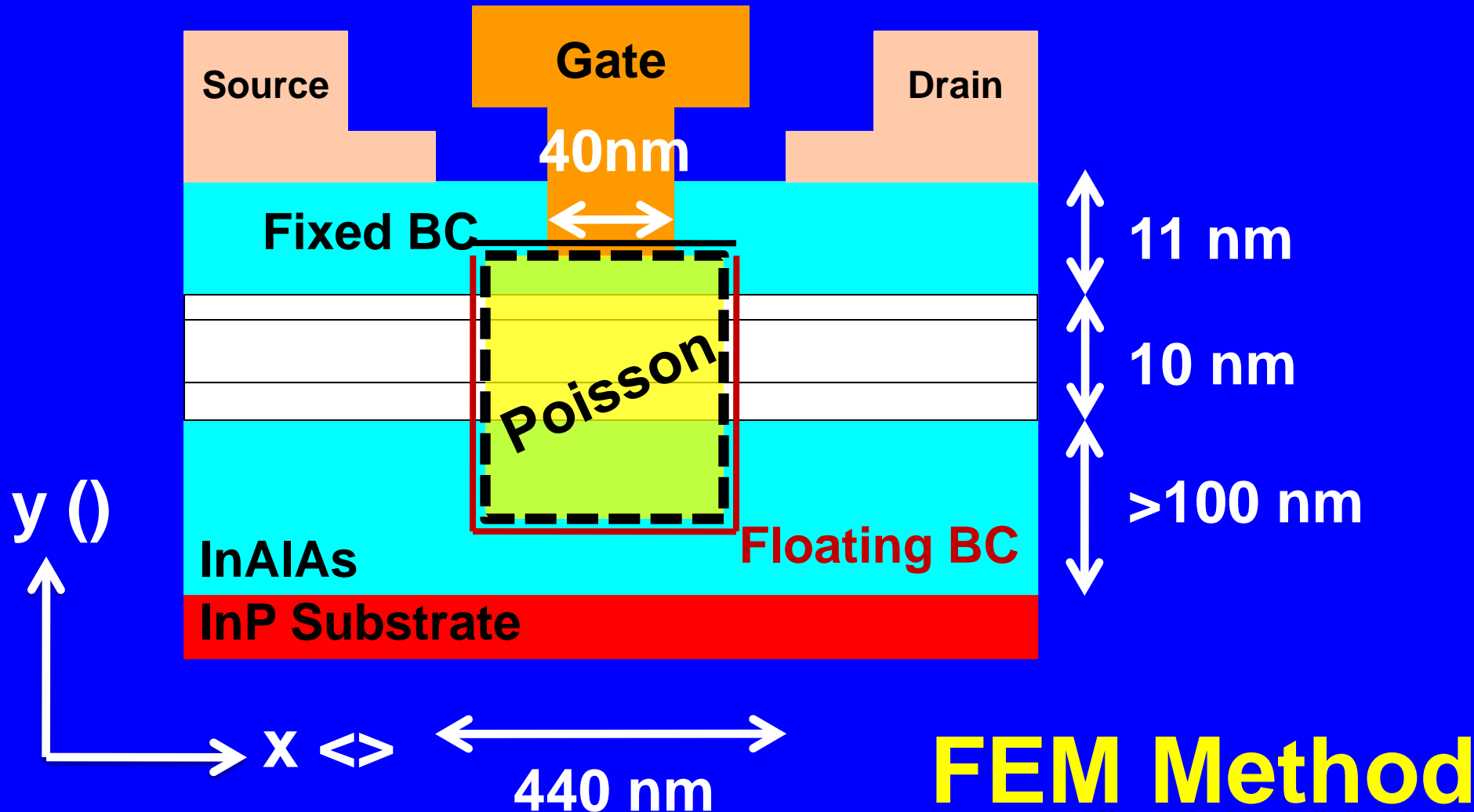
# Multi-Scale Domain Decomposition (2)

**Strain: Long Range Effect down to InP (1.4M Atoms)**



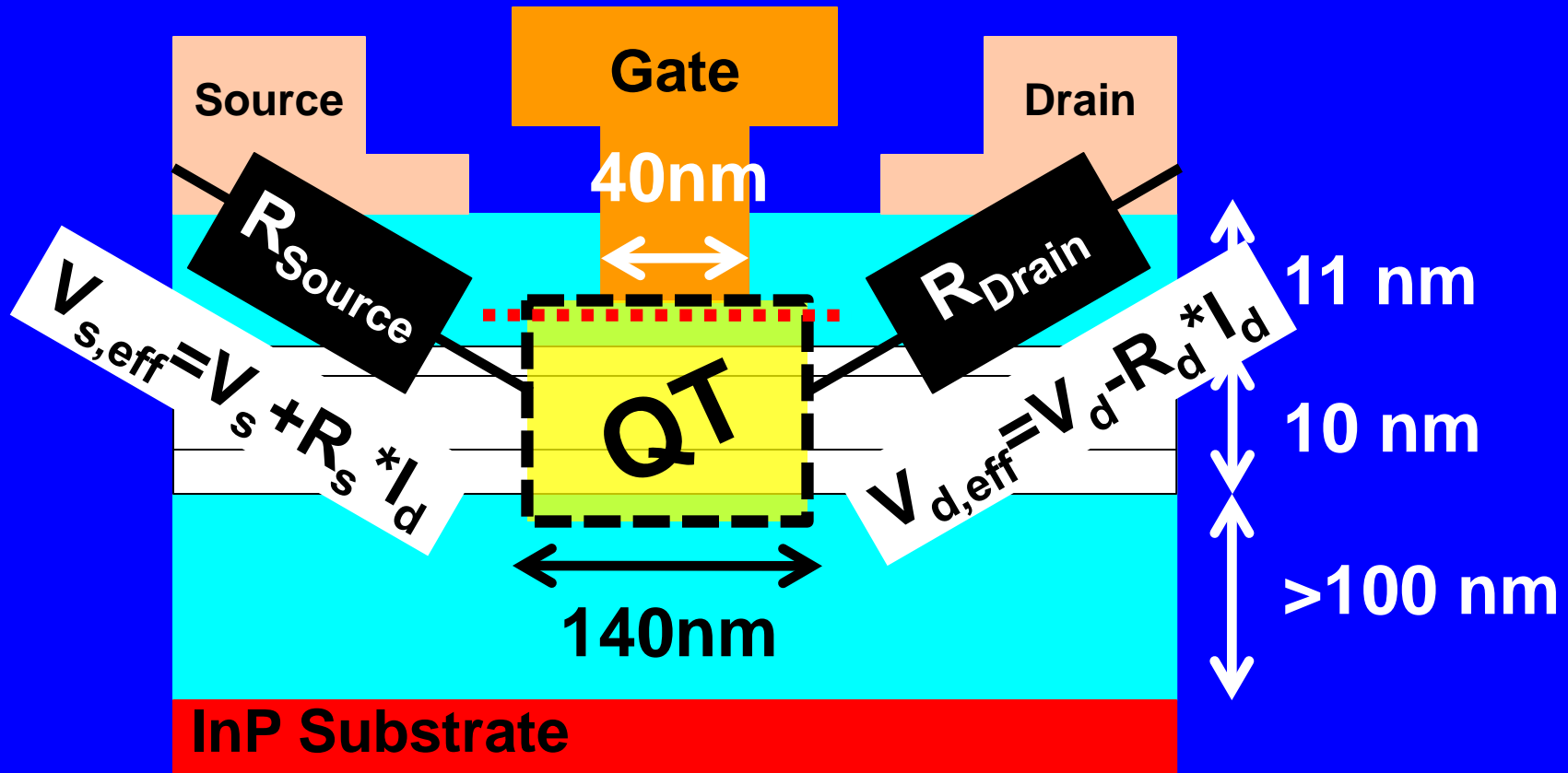
# Multi-Scale Domain Decomposition (3)

## Electrostatic Potential (Poisson): Fields in InAlAs



# Multi-Scale Domain Decomposition (4)

Quantum Transport: 140x14 nm<sup>2</sup> area (38,556 Atoms)



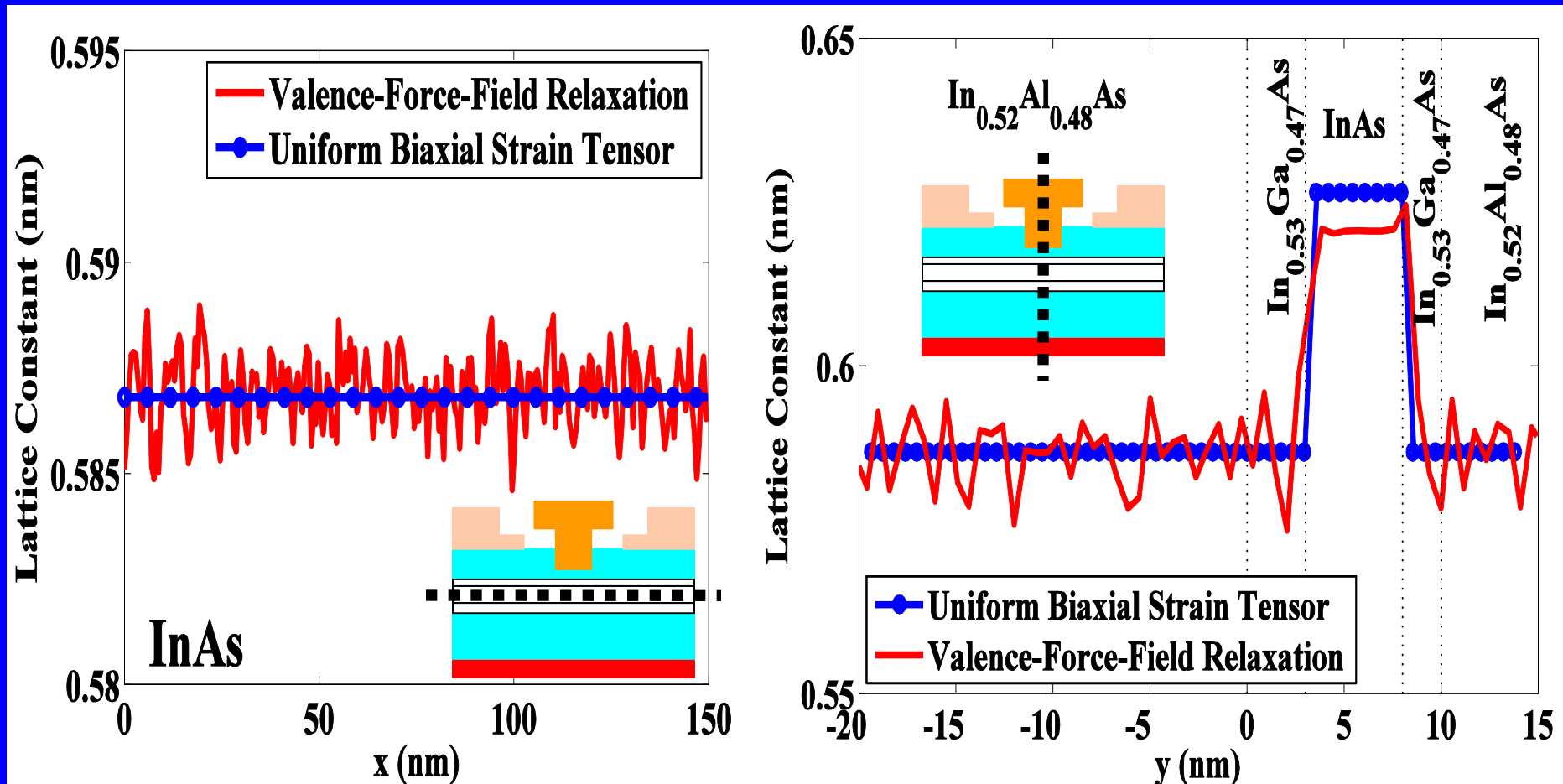
$$R_s = R_d = 190 \Omega \cdot \mu\text{m}$$

**Tight-Binding**

# Performance Analysis

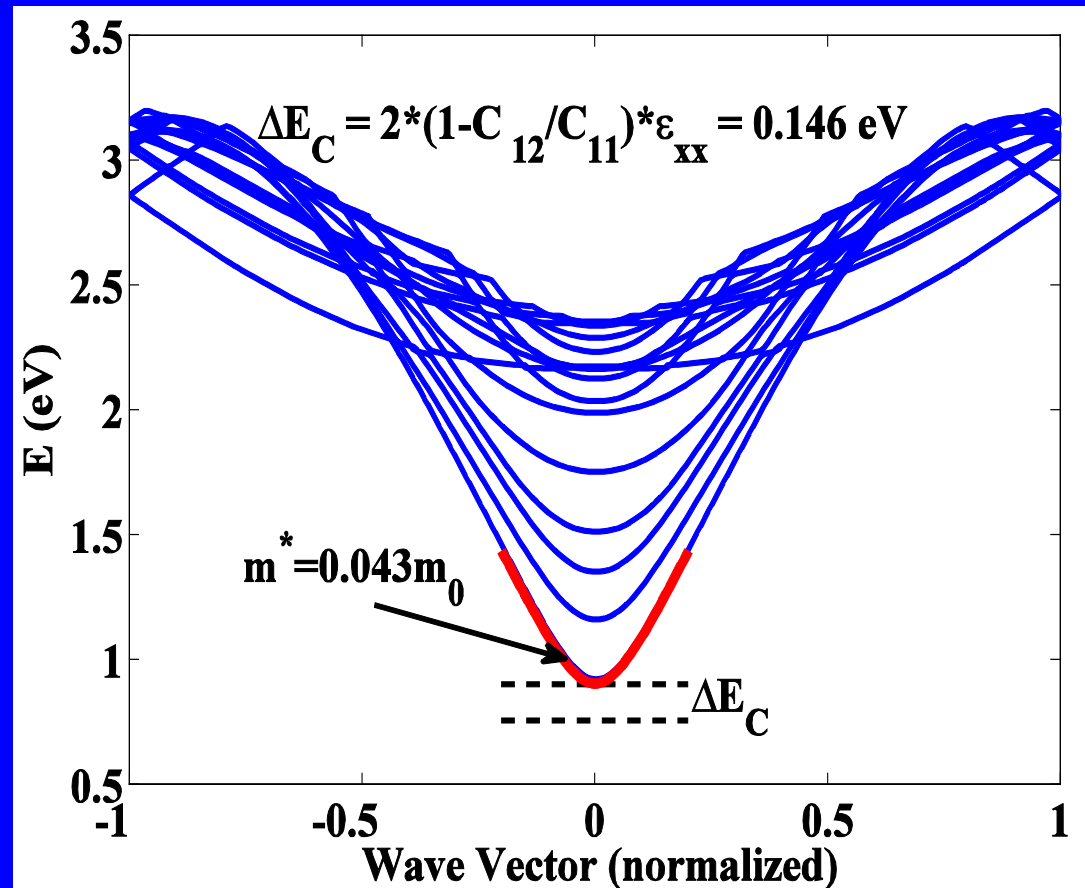
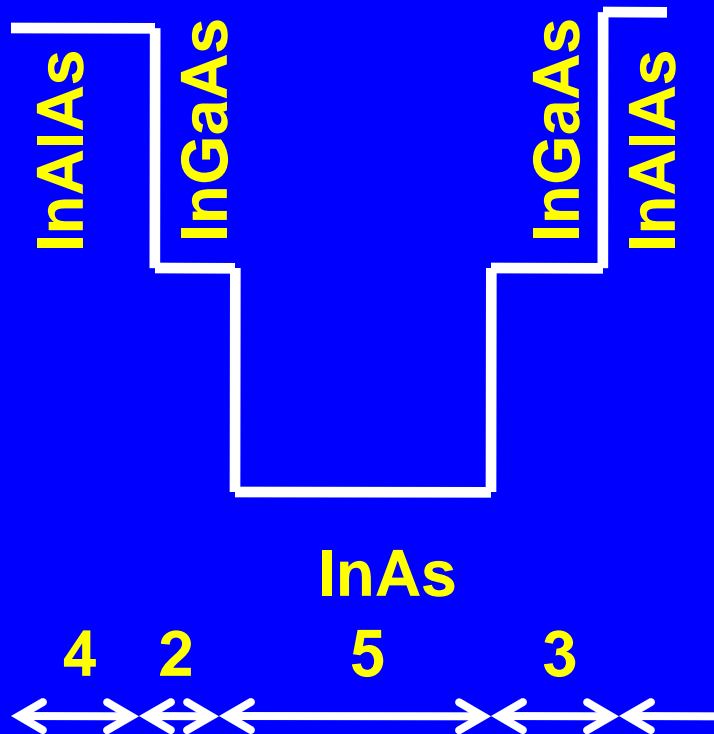
# Strain Profile: Alloy Disorder

Lattice Constant along ( $a_x$ ) and across ( $a_y$ ) the InAs QW  
InAs on  $\text{In}_{0.53}\text{Ga}_{0.47}\text{As}$  => Biaxial Compression along x and z



# Bandstructure of the MQW Region

Two Effects: 1) Band Gap Increase (Biaxial Strain)  
2) Effective Mass Increase (QW Width)

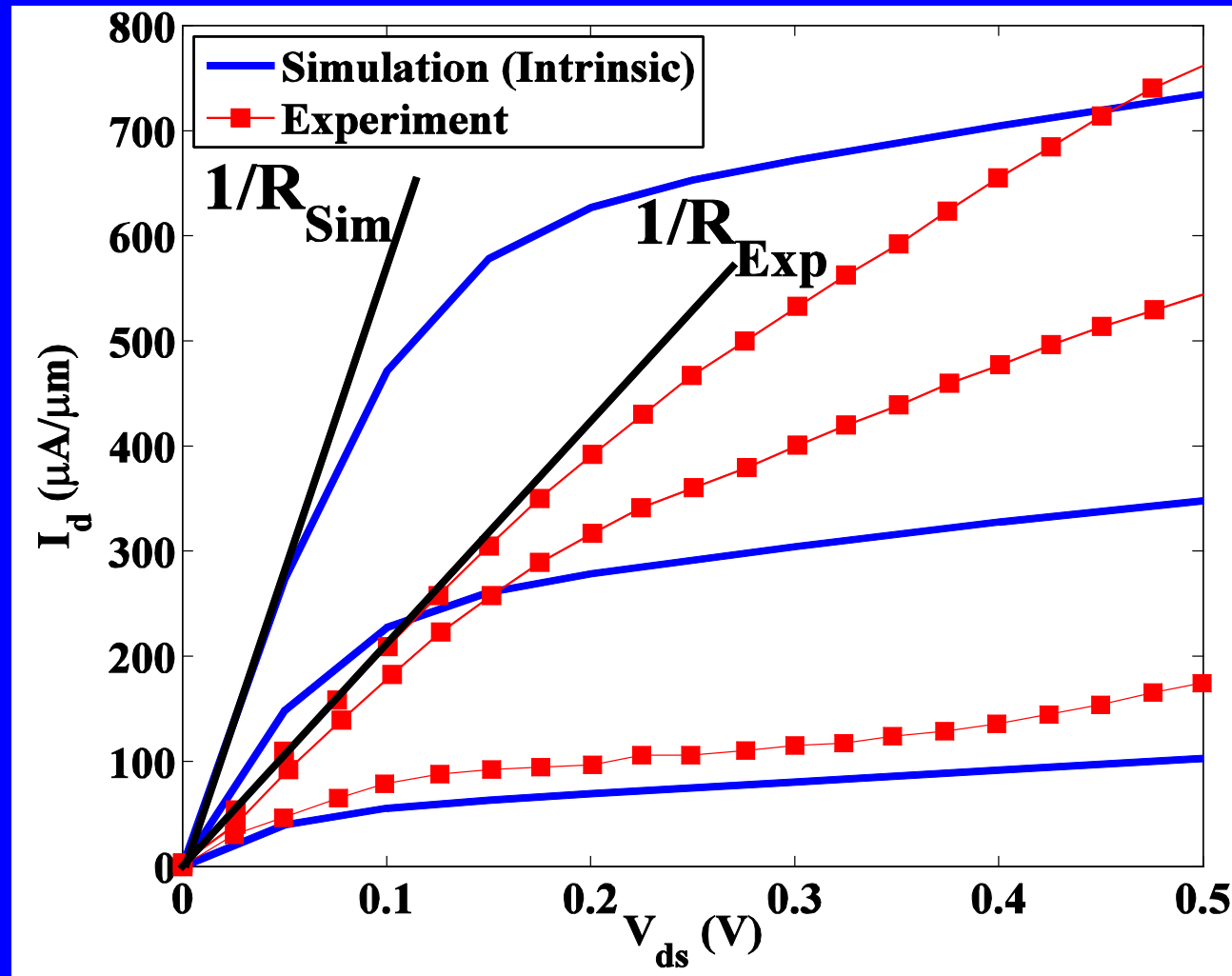




# Intrinsic Output Characteristics

Comparison with Measurement => 2 Discrepancies

(1) Simulated Resistance much too Low, (2) Current too High



$V_{gs}=0.40$  V

$V_{gs}=0.15$  V

$V_{gs}=0.20$  V

$V_{gs}=0.05$  V

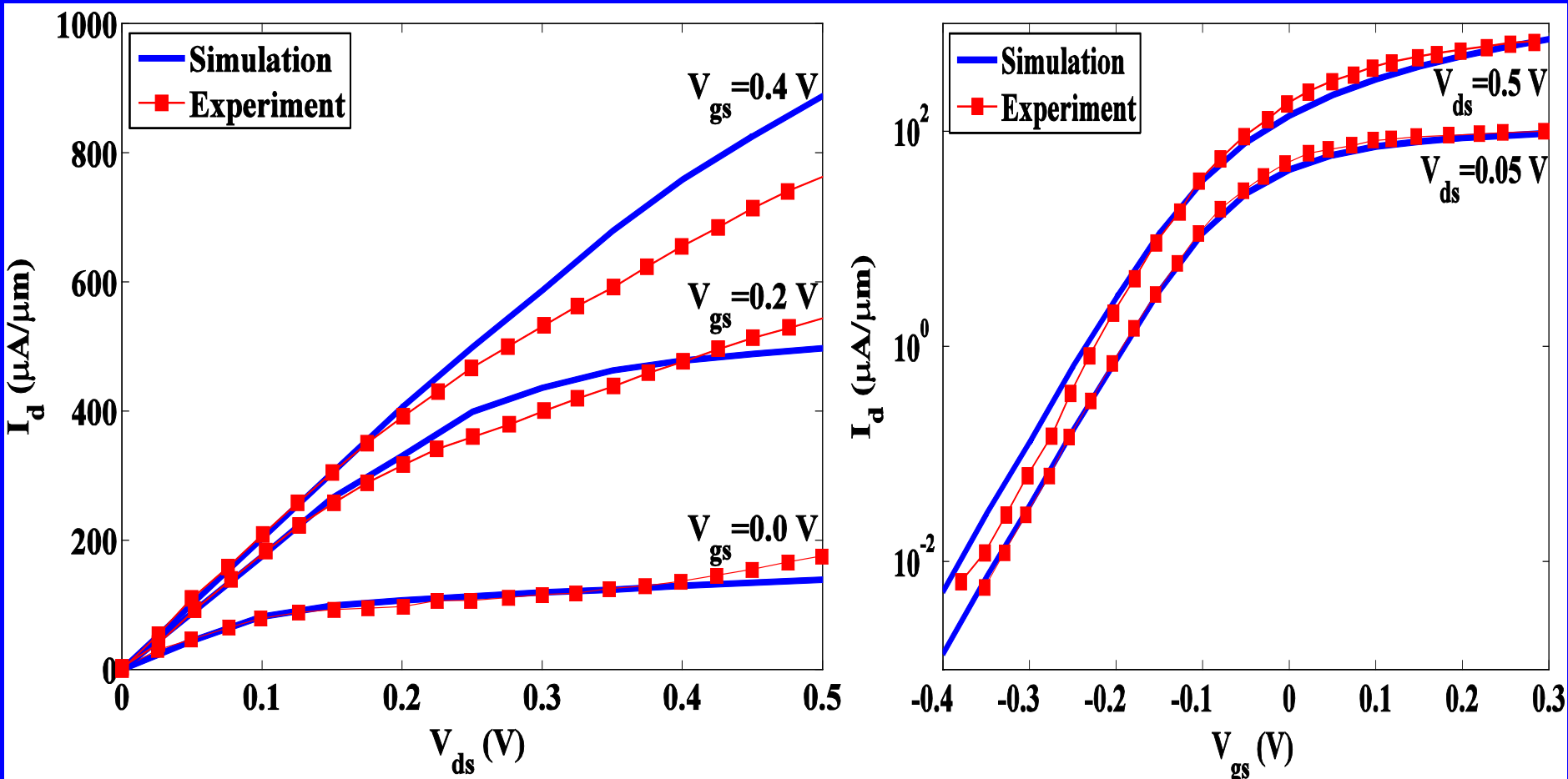
$V_{gs}=0.0$  V

$V_{gs}=-0.05$  V

# Current Characteristics

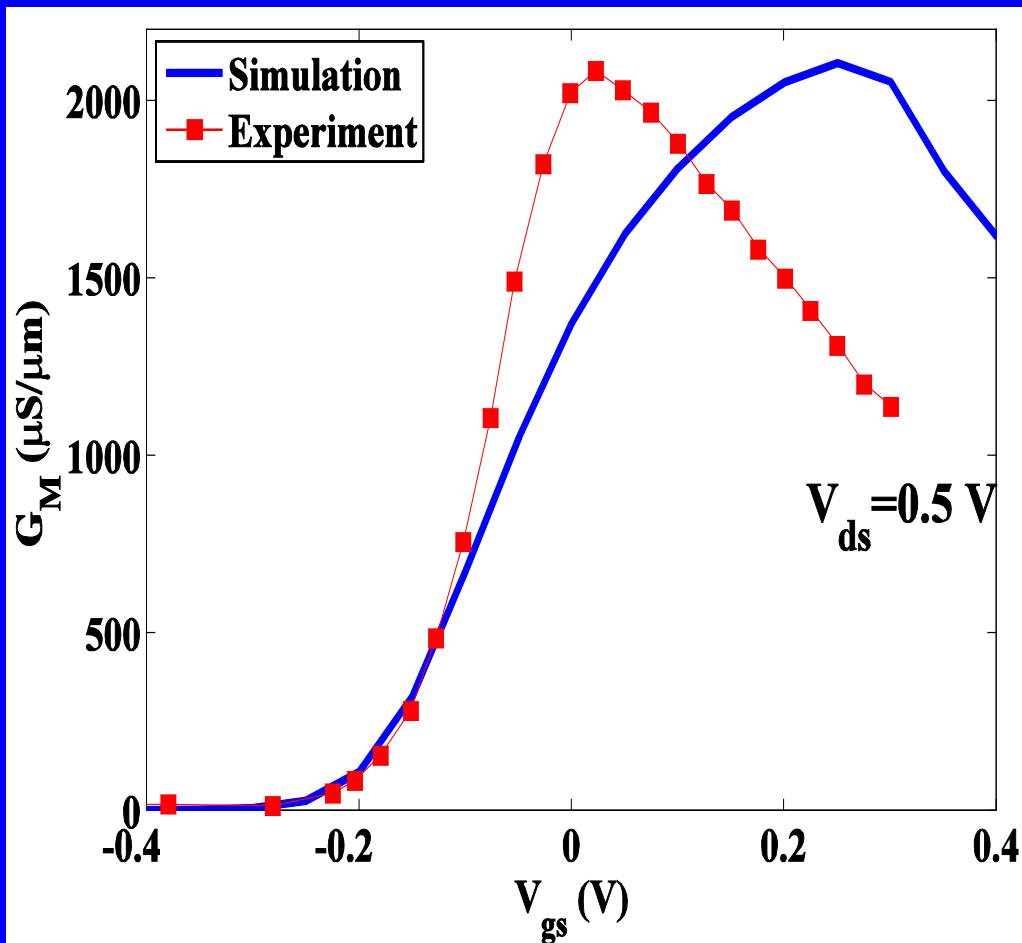
$I_d$ - $V_{ds}$  and  $I_d$ - $V_{gs}$  with Source and Drain Resistances

Simulated ON-current still too High: not Completely Ballistic?



# Transconductance $G_M$

Turn-ON and Maximum of  $G_M$  Correct, not the Slopes  
Decrease of Simulated  $G_M$  due to Source Starvation  
Source Resistances is not the Limiting Factor of  $G_{M,Lim}$



$$G_M = di_d/dV_{gs}$$

$$= di_d/dV_{gseff} \times dV_{gseff}/dV_{gs}$$

$$V_{gseff} = V_{gs} - R_s \times i_d$$

$$G_M = \frac{di_d/dV_{gseff}}{1 + R_s \times di_d/dV_{gseff}}$$

$$G_{M,Lim} \approx 1/R_s$$
$$\approx 5e3 \mu S/\mu m$$

# Summary of Performances

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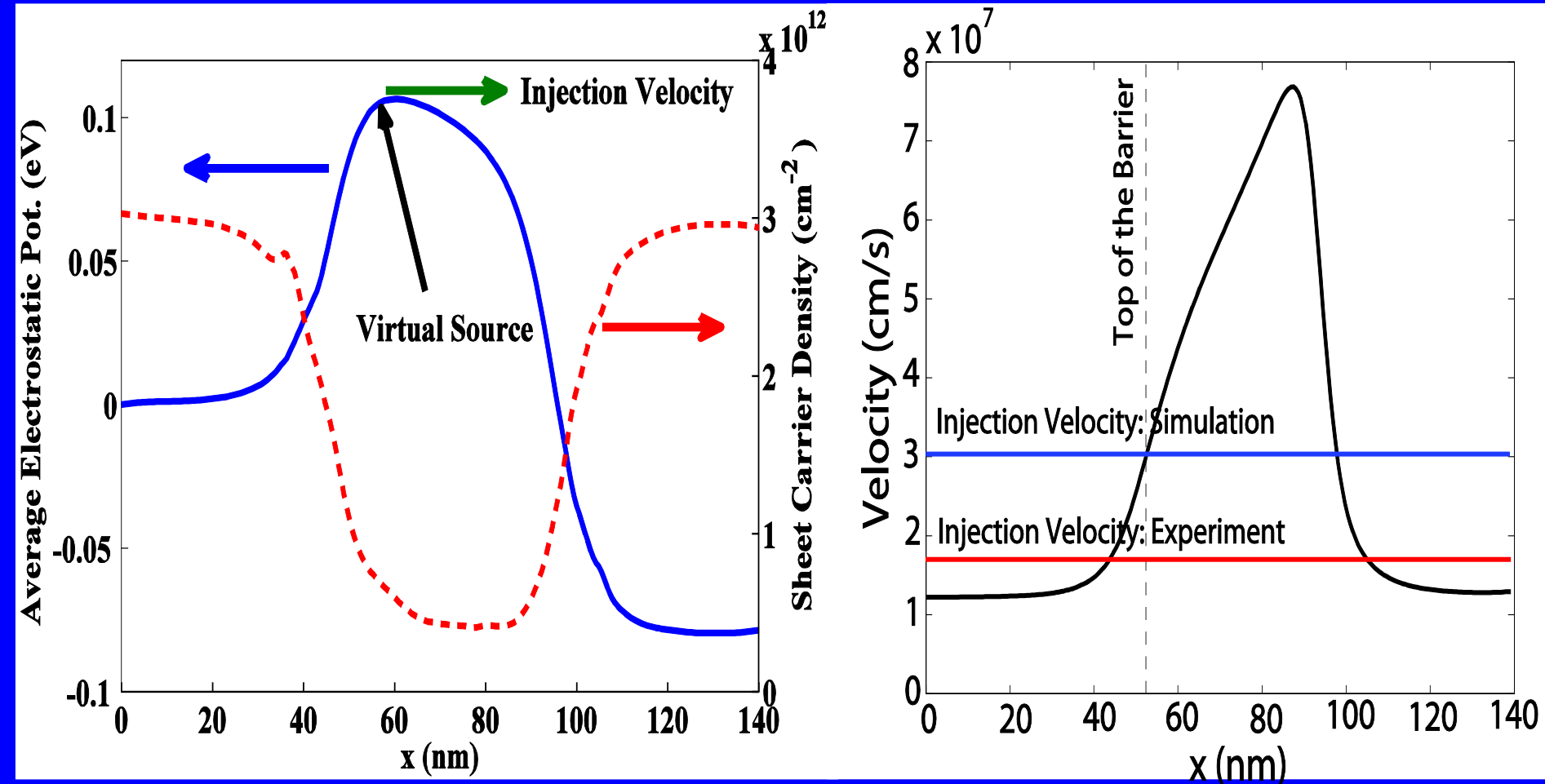
**Transistor Parameters from Simulation and Experiment:  
ON-Current, Threshold Voltage, Subthreshold Swing, DIBL,  
Maximum of Transconductance, and Injection Velocity**

	Experiment	Simulation
$V_{CC}$ (V)	0.5	0.5
$I_{ON}$ at $V_{gs}=0.3$ V ( $\mu A/\mu m$ )	656	676
$V_{th}$ (V)	-0.23	-0.23
SS (mV/dec.)	70	72.7
DIBL (mV/V)	80	96
$G_{max}$ ( $\mu S/\mu m$ )	2083	2105
$n_{2D}$ in Channel ( $cm^{-2}$ )	2.9e12	2.9e12
Injection Velocity (cm/s)	1.7e7	3.0e7

# Challenges and Open Issues

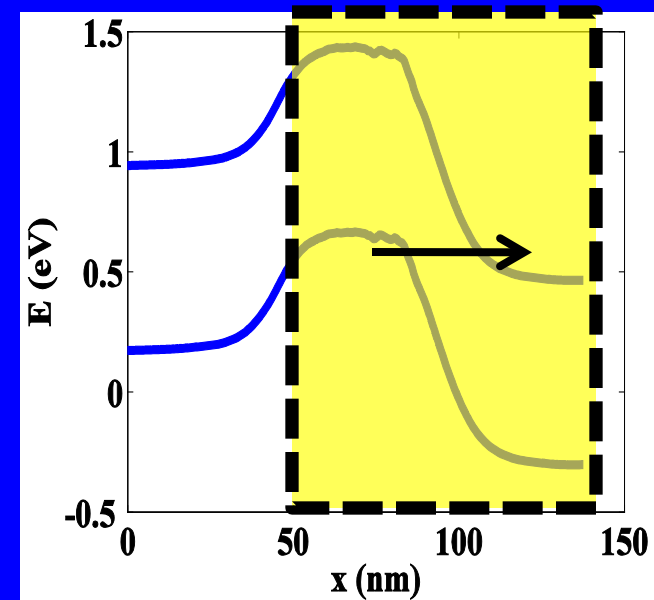
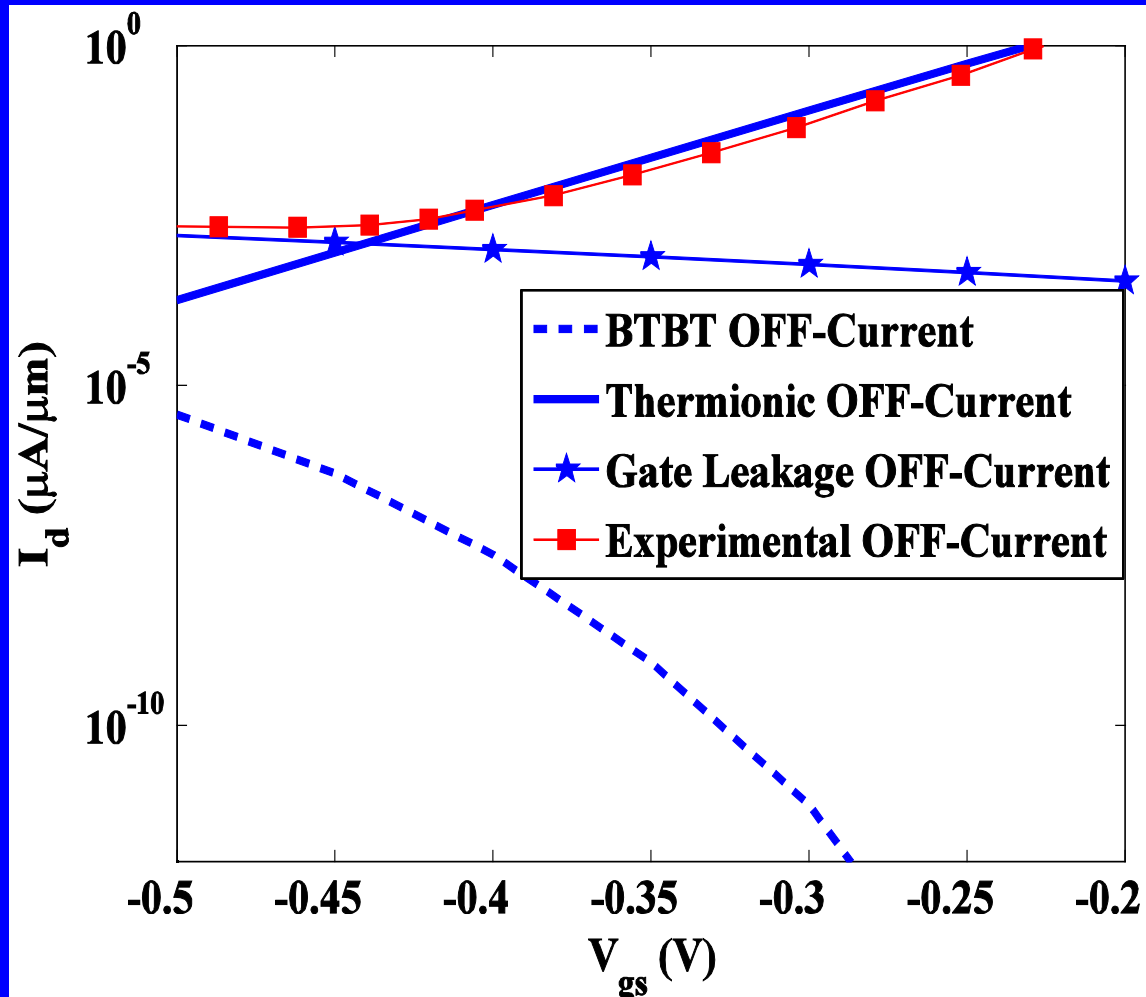
# Injection Velocity

**Injection Velocity at Virtual Source:  $J = q \times N_{\text{dens}} \times v_{\text{inj}}$**   
**Simulated Velocity Overestimates Measurement by 1.76x**



# Leakage Currents: BTBT and Gate

BTBT OFF-Current Added as a Post-Processing Simulation  
Gate Leakage OFF-Current under Investigation (EM Model)



**BTBT Sim. Domain  
After SC Calculation  
FB Required**

# Conclusion and Outlook

- **Quantum Transport Simulator**

Full-Band and Atomistic  
III-V HEMTs

- **Performance Analysis**

Good Agreement with Experiment  
Some Open Issues

- **Outlook**

Improve Models (Contact)

Investigate Scaling of Gate Length  
Scattering?

